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Sheet	1	of	2												

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Examiner Signature		Date Considered	
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**INFORMATION DISCLOSURE  
STATEMENT BY APPLICANT**

(use as many sheets as necessary)

Sheet 2 of 2

**Complete if Known**

Application Number	
Filing Date	October 14, 2003
First Named Inventor	Enzo Carollo
Group Art Unit	
Examiner Name	
Attorney Docket Number	2110-81-3

**OTHER PRIOR ART -- NON PATENT LITERATURE DOCUMENTS**

Examiner Initials *	Cite No. <sup>1</sup>	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T <sup>2</sup>
		J. YOTA, et al., "Comparison Between HDP CVD and PECVD Silicon Nitride for Advanced Interconnect Applications", 0-7803-6327-2/00 2000 IEEE, pp. 76-78	
		J. YOTA, et al., "A Comparative Study on Inductively-coupled Plasma High-density Plasma, Plasma-enhanced, and Low Pressure Chemical Vapor Deposition Silicon Nitride Films", J. Vac. Sci. Technol. A 18(2) Mar/Apr 2000 0734-2101/2000/18(2)/372/5 2000 American Vacuum Society, pp. 372-375	
		S. V. NGUYEN, "High-density Plasma Chemical Vapor Deposition of Silicon-based Dielectric Films for Integrated Circuits", 0018-8646/99 1999 IBM, 21 pages	
		European Search Report for EP 02 42 5615 dated May 7, 2003	

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